



FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
(REV. 2-32) PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.

47265.27

SERIAL NO.

10/560,122

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

APPLICANT
Manfred Faubel, et al.

FILING DATE

8 December 2005 (371 date)

ART UNIT 2882

~~Not Yet Assigned~~

Customer Number: 23973

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05/04/2011

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